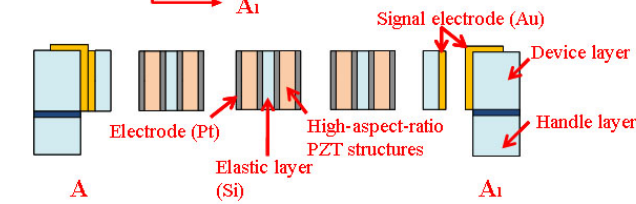
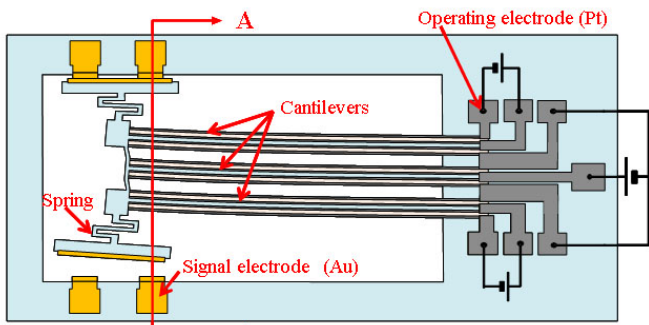
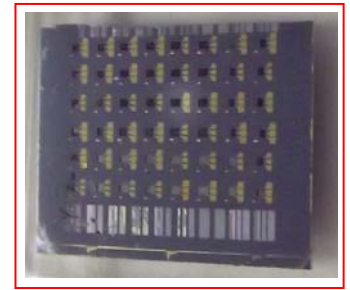
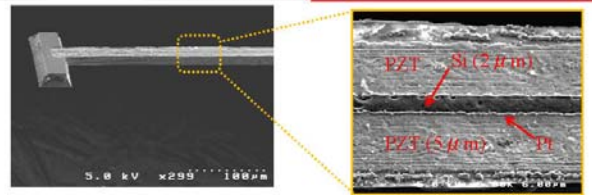
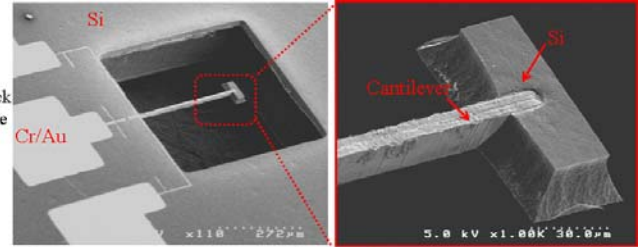


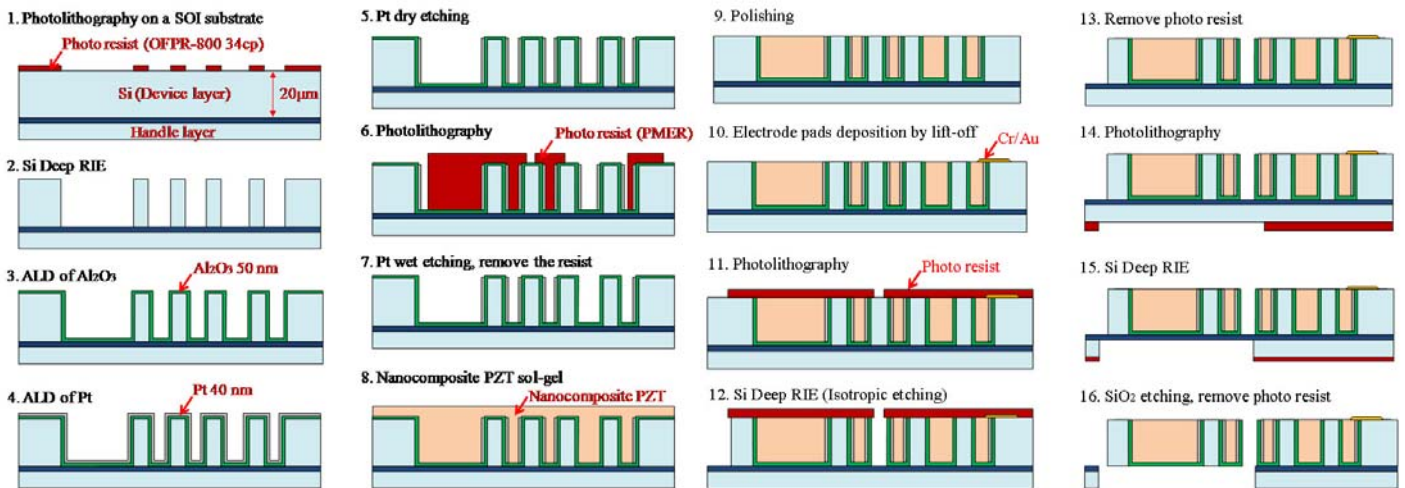
# Lateral Motion Piezoelectric Microactuator



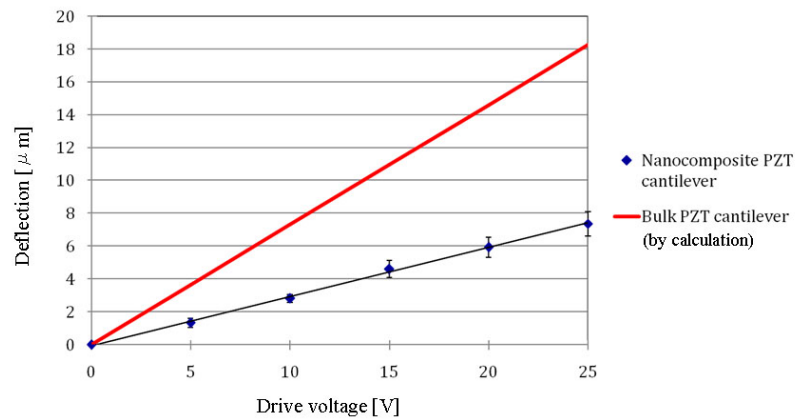
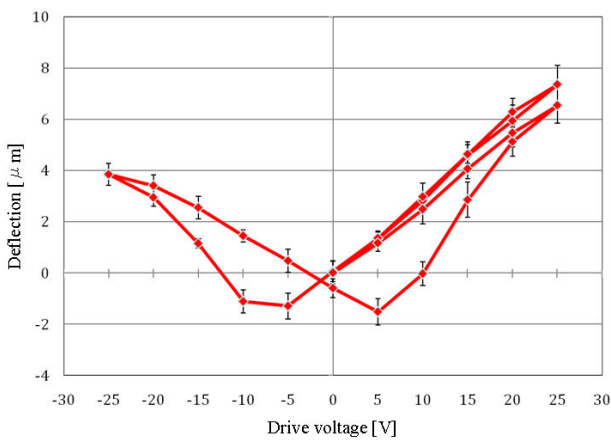
Structure



Photograph



Fabrication



Displacement versus voltage

Lateral motion piezoelectric microactuator

Reference : N.Wang, S.Yoshida, M.Kumano, Y.Kawai and M.Esashi, Fabrication of High-aspect-ratio PZT Structure by Nanocomposite Sol-gel Method for Laterally-driven Piezoelectric MEMS Switch, 2012 7<sup>th</sup> IEEE Intl. Conf. on Nano/Micro Engineered and Molecular Systems (IEEE NEMS 2012) (2012) pp.321-326